

Quantum Efficiency and Noise

III-V and II-VI Photocathodes

for UV Astronomy

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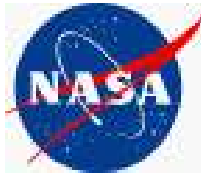
Overview



- **Our photocathode application in UV space-based astrophysics**
- **Current NUV (100 - 320 nm) photocathodes and detectors - QE problem**
- **Gallium nitride (and alloys) a high QE III-V photocathode**
- **Our experience processing planar - opaque mode GaN and measuring GaN quantum efficiency**
- **Summary of the status of ours and others GaN work**
- **Nano-structuring GaN**
- **Noise**
- **ZnO a II-VI photocathode candidate**
- **Conclusions**



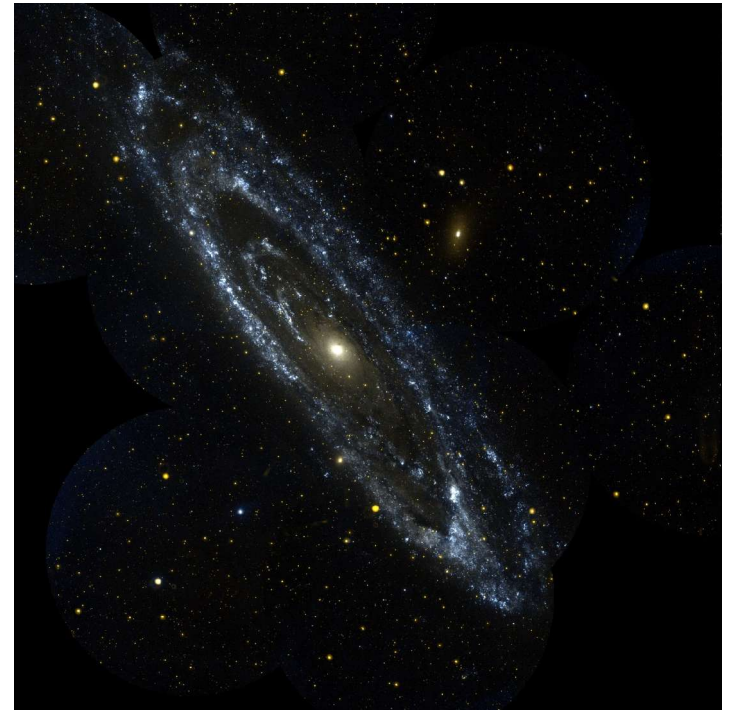
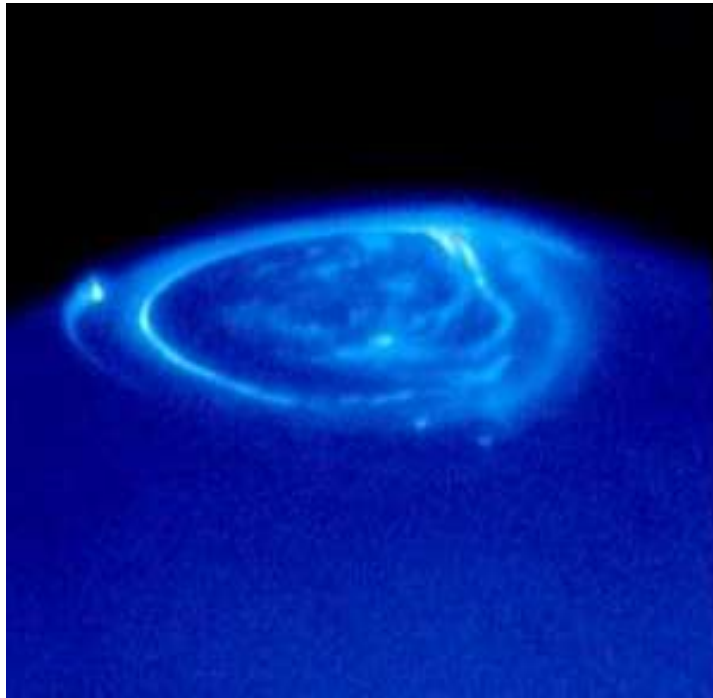
NUV photon-counting detector detector QE



MCP based UV photon-counting detectors are the workhorses of UV astronomy. (EBCCD/CMOS detectors can also serve as useful UV photon counting detector readout)

- **They utilize a variety of photoemissive layers as the primary detection medium.**
- **For space-based astronomy missions QE and noise are paramount factors**
- **QE scales directly to required mirror size – payload size, weight and cost**
- **High QE enables new science discovery reach**

State of the art - Photocathode based UV photon-counting detectors



HST-STIS/ACS/COS MAMA GALEX Delay line - UCB

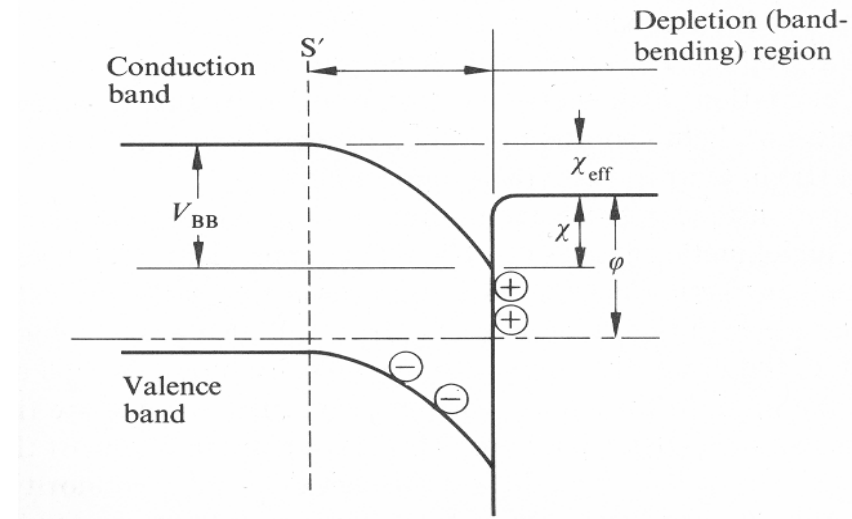
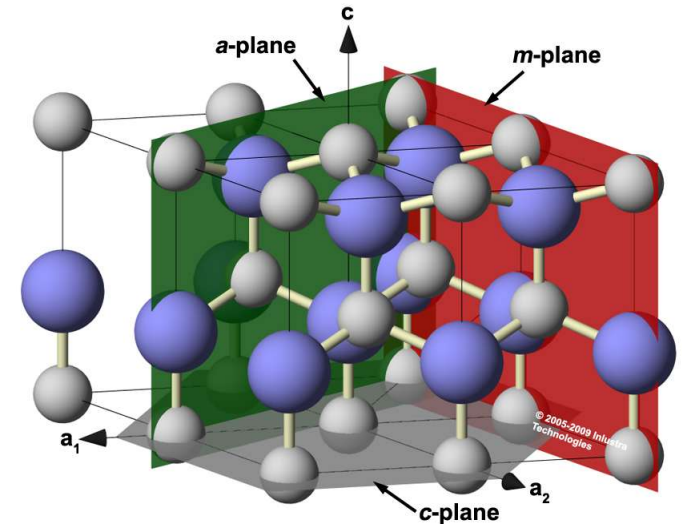
Excellent photon-counting detectors but they rely upon CsTe < 12% peak efficiency in the NUV. Their visible equivalents – CCDs – QE peak > 90 %



Gallium Nitride – a III-V photocathode



- GaN – Direct Band Gap material, 3.2eV
- Electron affinity 4.1 eV
- Can be cesiated to NEA
- Alloys – In for red response, Al for short wavelength cutoff
- Substrate match to sapphire
- Industry leverage – Blue LED – Bluray etc
- Photocathode development - active Groups : NASA GSFC, UCB, NWU, SVT Associates, POC/TDI and Hamamatsu.



After p-doping with Mg and cesiation - NEA



Spicer 3-step model



QE depends upon :-

- 1) Absorption of photon - Reflection
(angular dependence)
- 2) Electron- transit to the Surface
Random walk
e--e- scattering,
phonon - trap scattering
Transit through depletion layer
- 3) Escape surface probability
Overcome Work function
Reduction of Φ due to Cs dipole or
applied field (Schottky Effect)

Spicer 3-step diffusion model



P – Escape probability – P-doping, Cs/CsO), surface cleanliness.

R – Reflectivity - Morphology

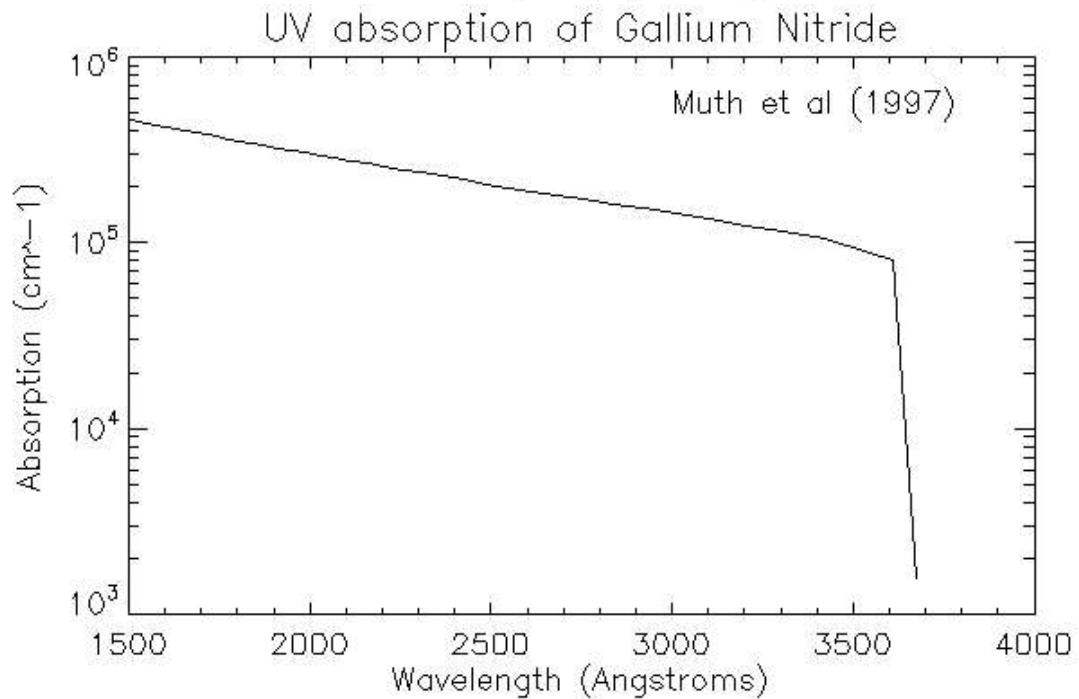
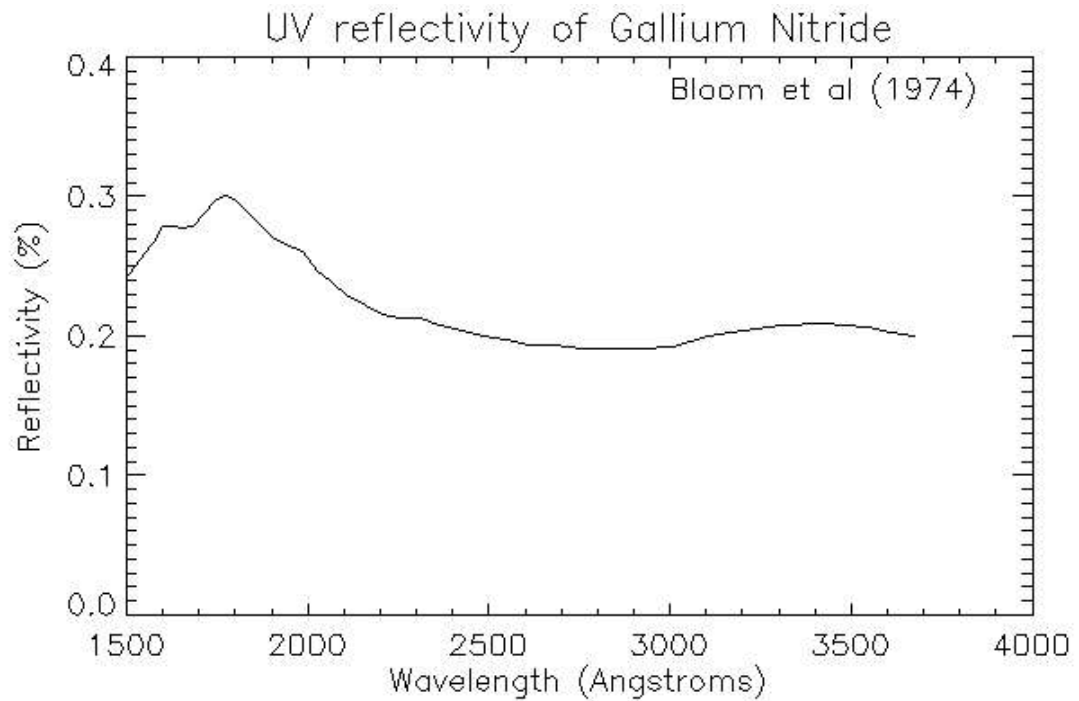
α – Absorption coeff – doping level.

L – Diffusion length – (doping level,traps,quality)

$$QE = \frac{P (1 - R(\lambda)) \alpha(\lambda)L}{1 + \alpha(\lambda) L}$$

For NEA cathodes : $\alpha(\lambda) L \gg 1$

$L > 1$ micron

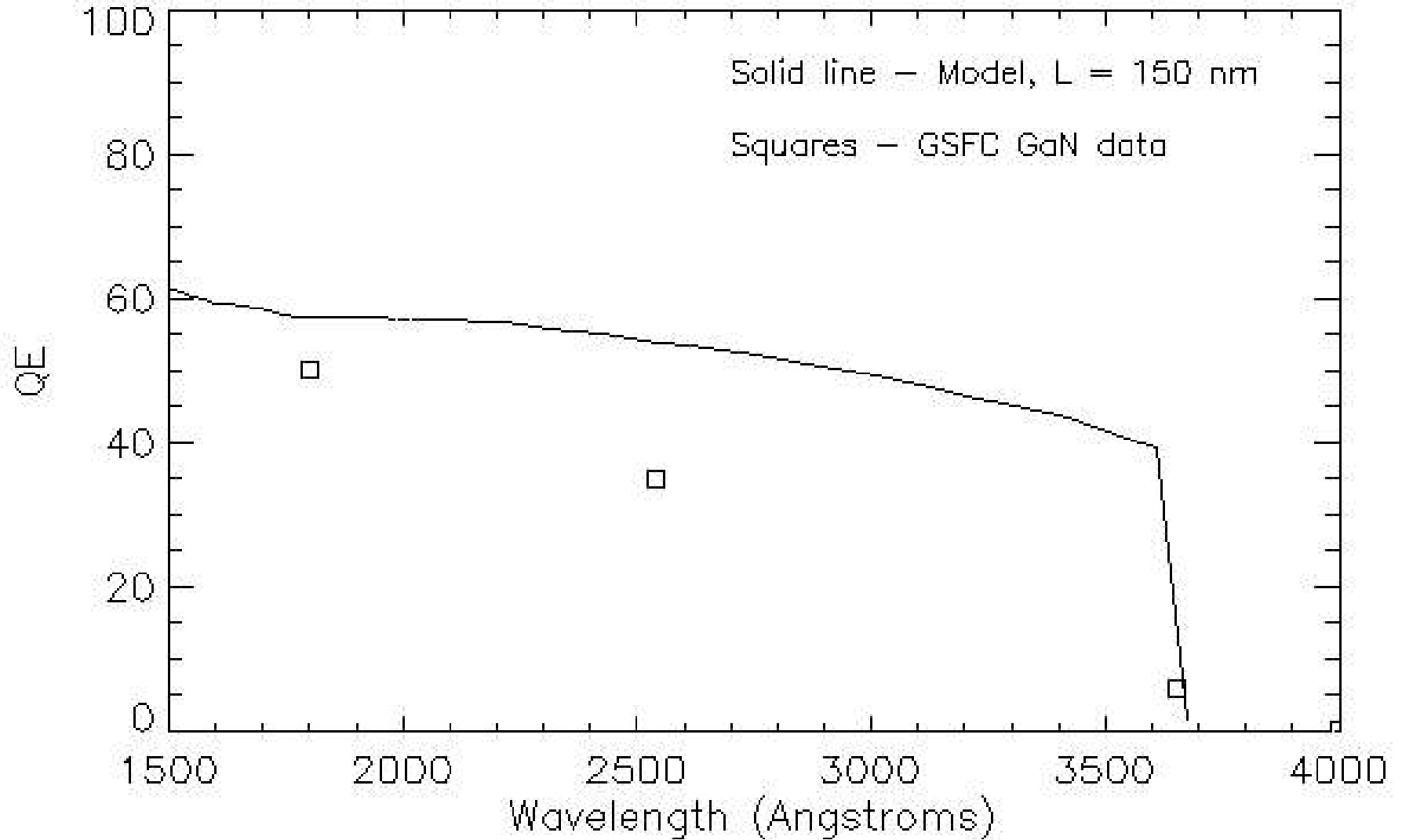




GaN QE – Model and data



Gallium Nitride QE in the NUV





GaN sample mounting



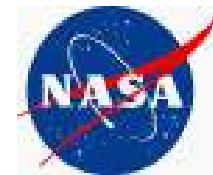
GaN suppliers :-

SVT Associates

NWU

TDI/Oxford
Instruments

NIST, CO



25 nm



nm

-37.6

1.0 μm

SVT

102120601-11

1.0 μm

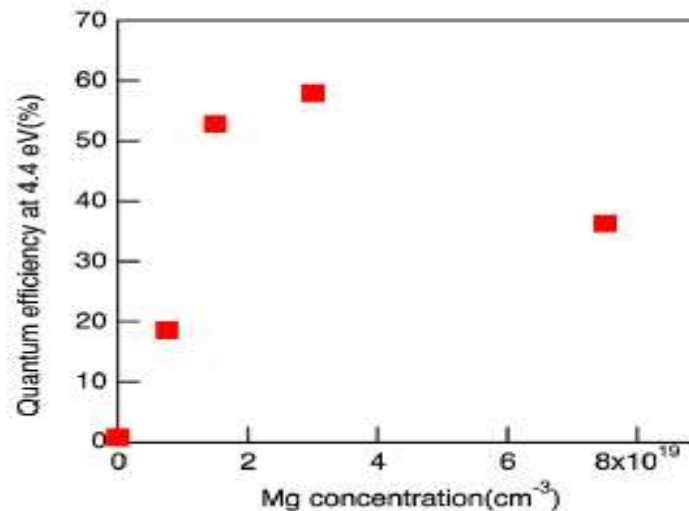
SVT 0.1 micron GaN, planar. Vertical scale magnified.

P-Doping – Band bending and escape probability



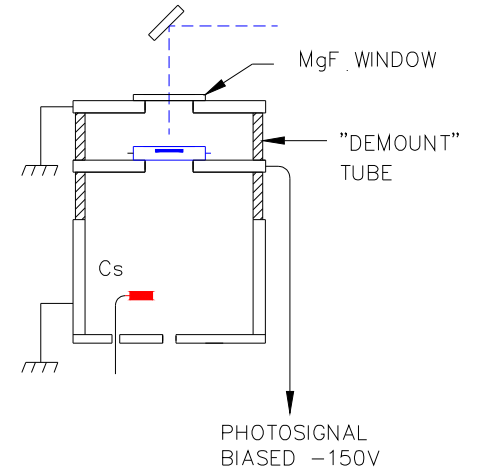
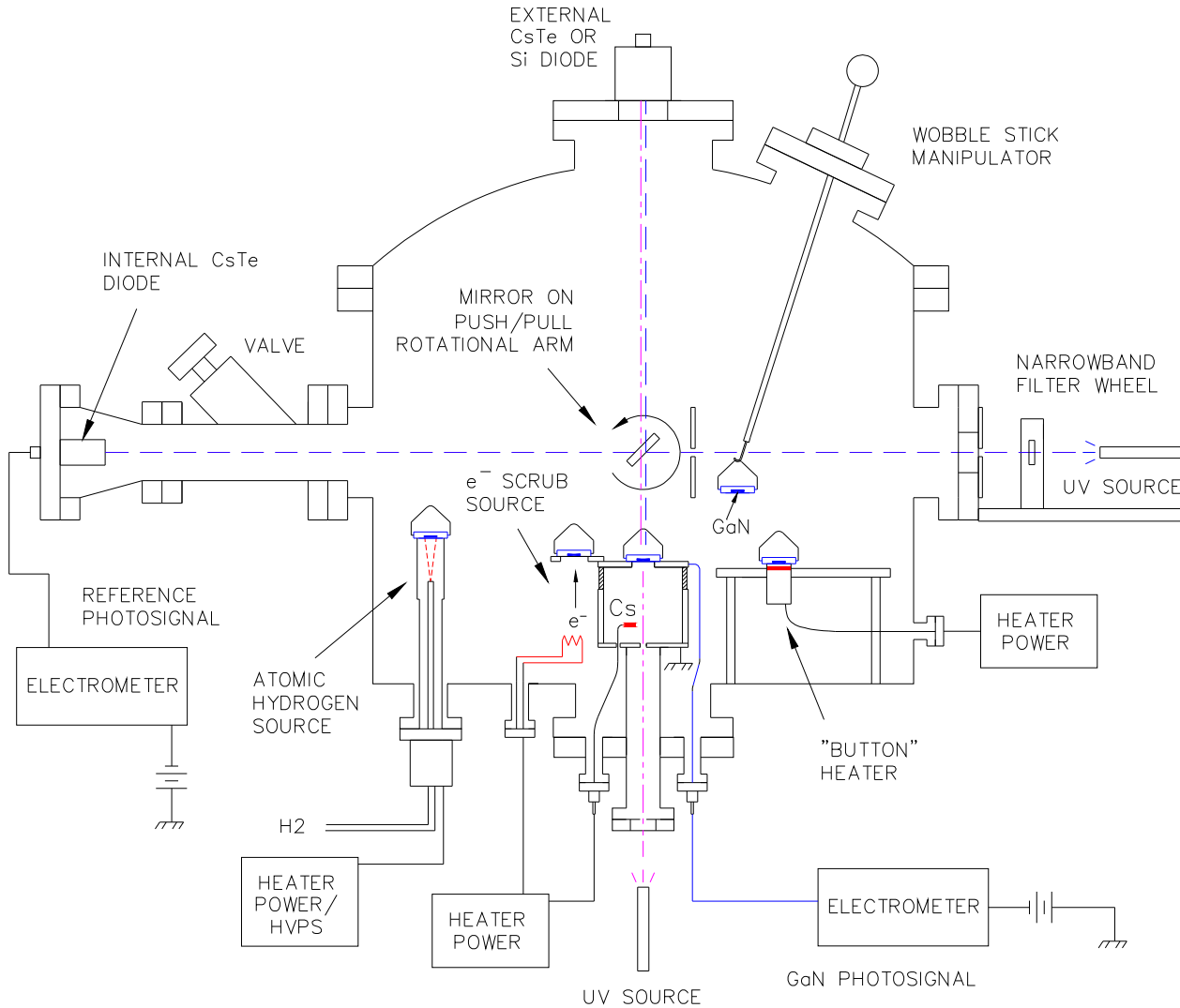
- Optimum acceptor (Mg) doping required for high QE.
- Too low results in minimal band bending – low escape probability.
- Too high increases minority carrier scattering and trapping.
- We (GSFC have too limited data set to verify optimum level)
- Hamamatsu Inc (Uchimaya) show $3 \times 10^{19} \text{ cm}^{-3}$ optimum level.

Appl. Phys. Lett. 86, 103511 (2005)

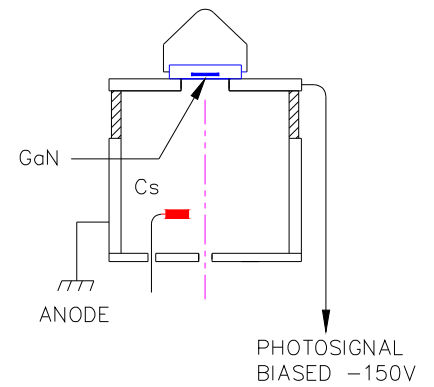




Photocathode processing chamber

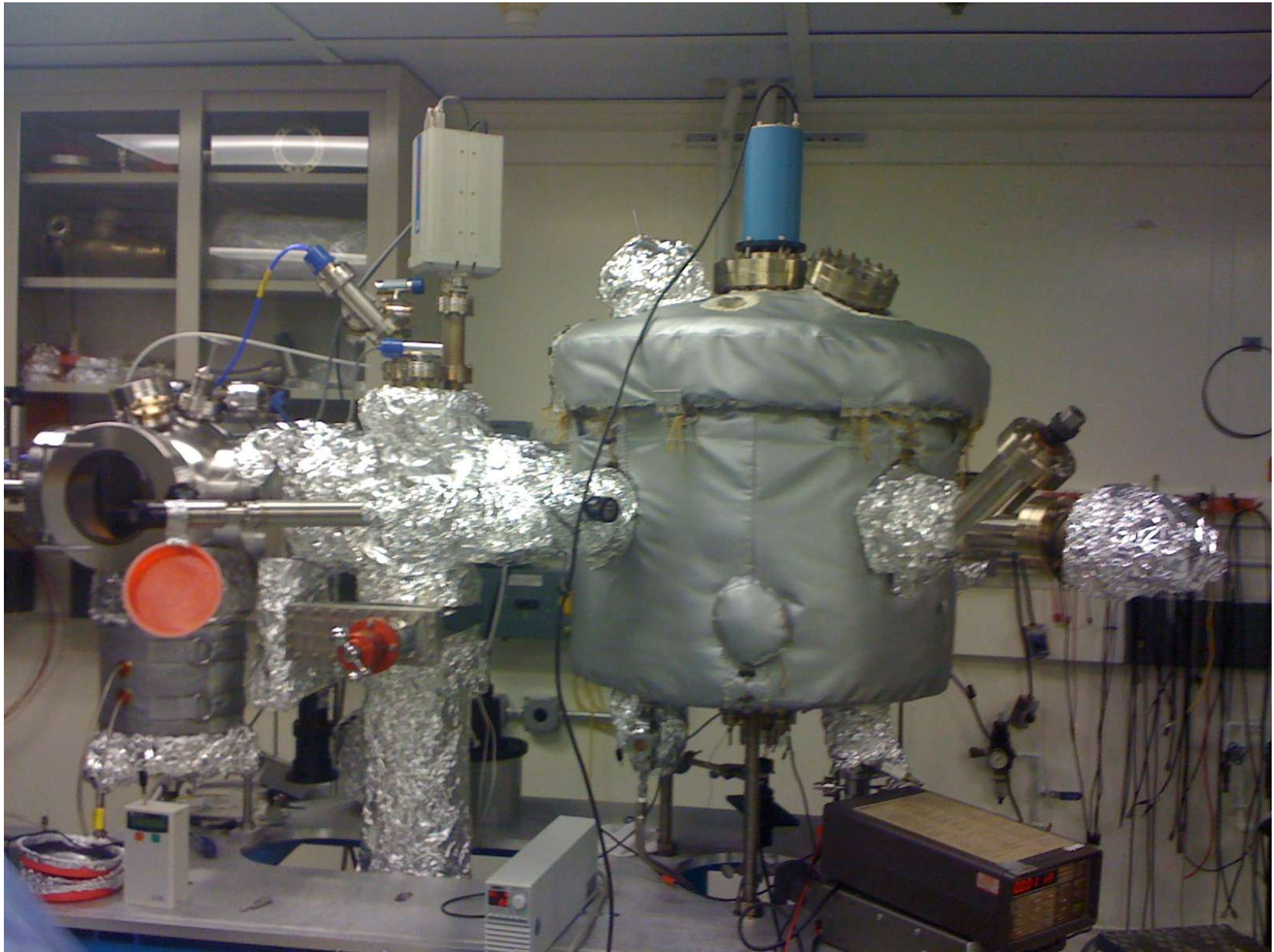
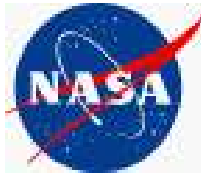


CALIBRATION POSITION



CESIATION POSITION

Photocathode processing and transfer chamber

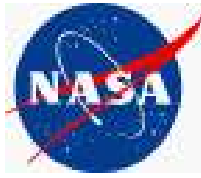


GaN annealing, cesiation and calibration





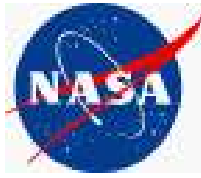
Basic GaN photocathode process



- **Acquire p-GaN – Vendors, SVT, TDI, NWU, NIST.**
- **Cut into 1 cm squares – mount into sample holders.**
- **Wet etch – Pirahna + HF, DI rinse – N2 bagging.**
- **Button heater anneal > 2 hrs at 600C.**
- **Electron scrub – 300 eV electrons, 1600 microamp/hrs.**
- **Cesiation – SAES sources – 15 minute process – over cesiate.**
- **Calibrate at 121, 150, 180, 254 nm vs CsTe – NST calibrated diode.**
- **Decision to seal into device.**



Surface preparation is crucial !



Piranha wet etch :-

H₂SO₄ + H₂O₂ (3:1) 10 min.- 90C; DI H₂O rinse 5 min.; H₂O + HF (10:1) 10 sec dip; DI H₂O rinse 10 min.; Blow dry with N₂. Package in clean, sealed N₂-purged bag.

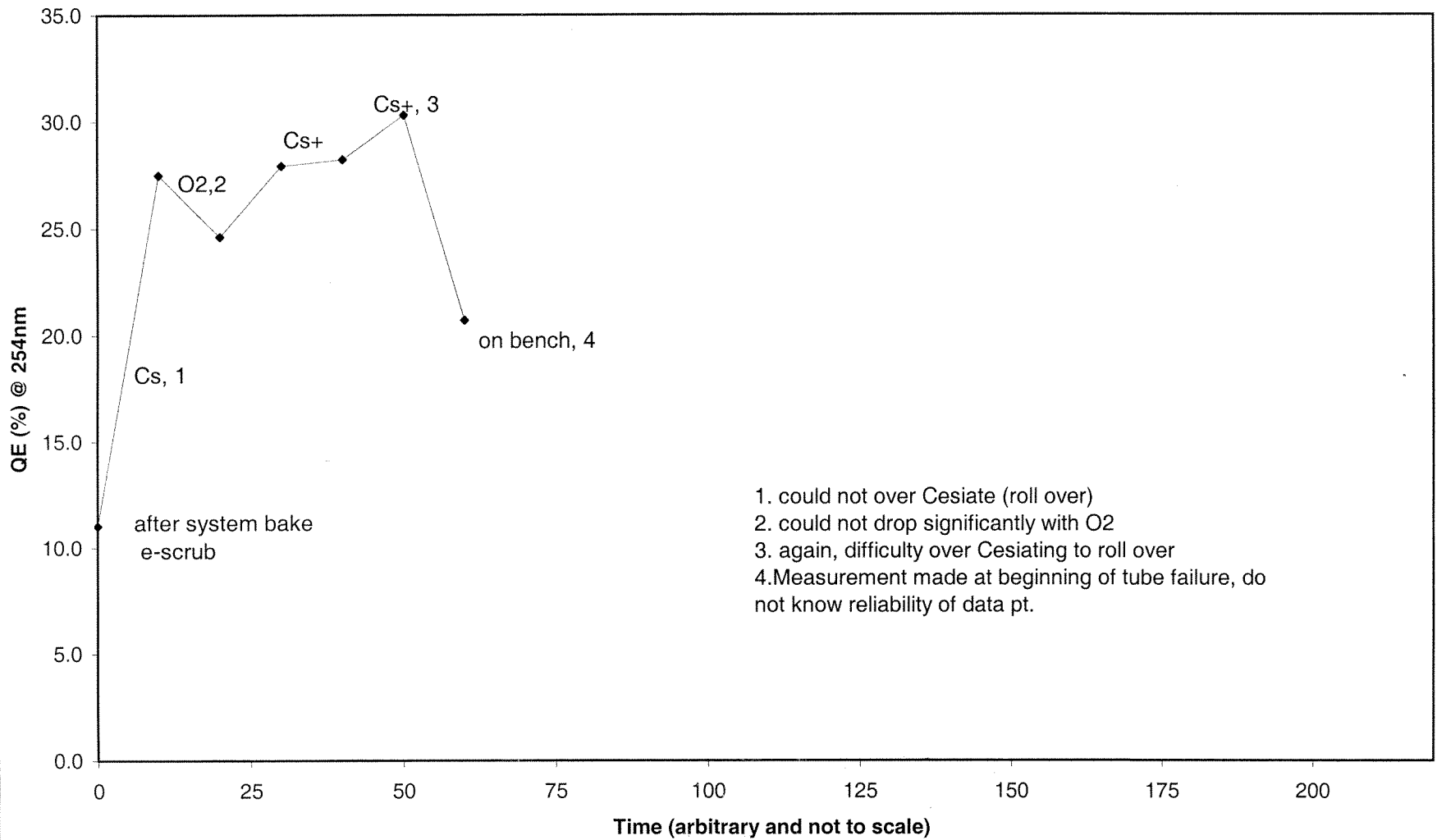
Vacuum bake – UHV chamber – 350 C – 24 hrs

Button heater - 600 C for 2 hrs

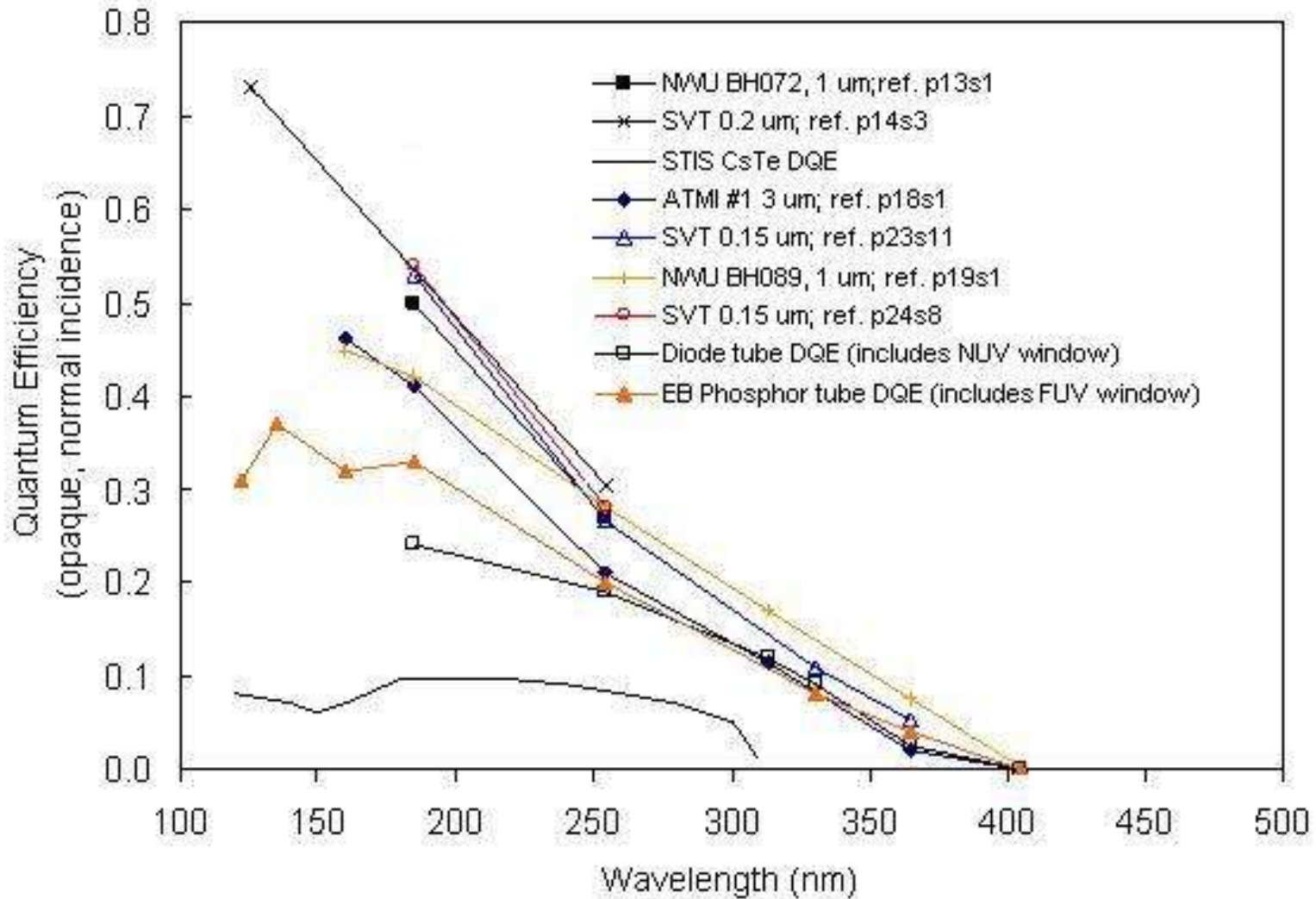
Electron scrub – 300 eV electrons – 160 μ/hr dose

Cannot overstate importance of these process steps in improving QE.

Process 20, Tube01, SVT 0.15um
QE vs. Processing



GSFC GaN processing - QE results

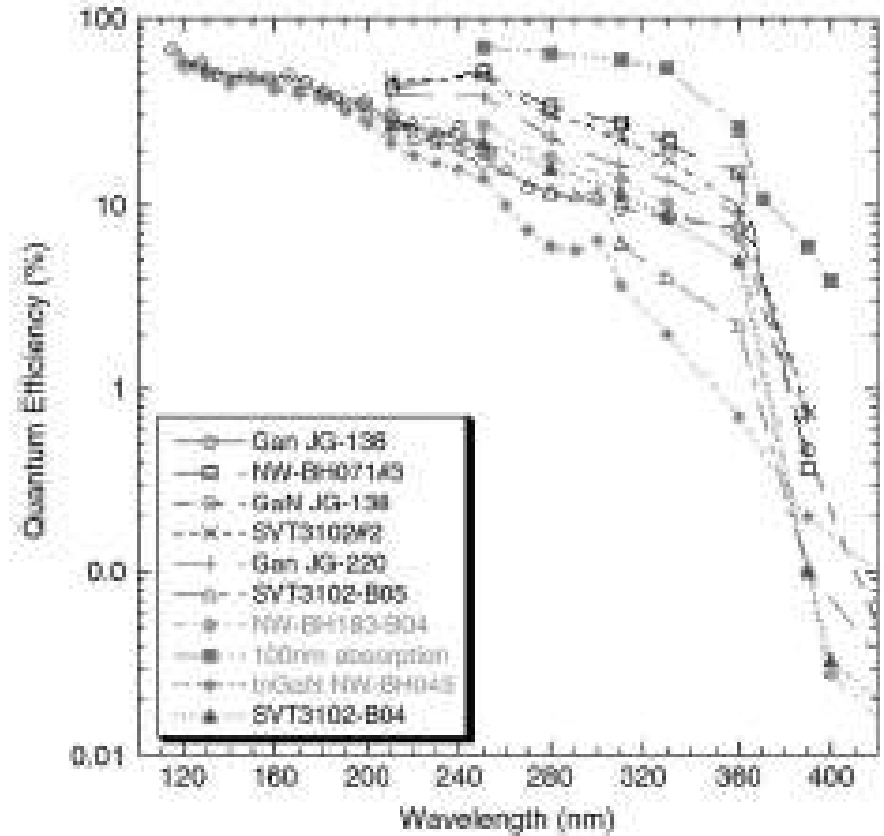
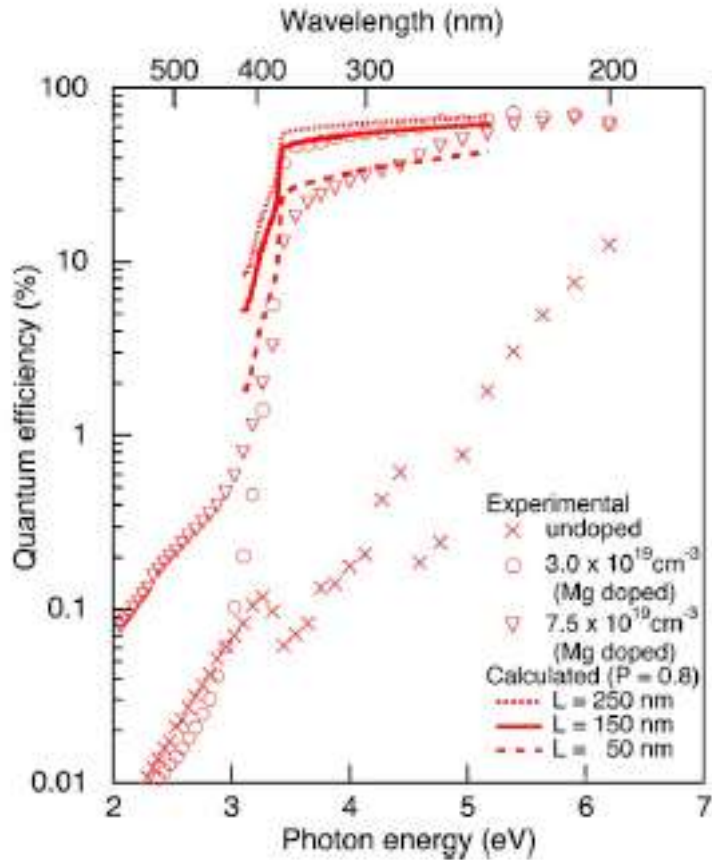




Opaque Gan QE - Progress



103511-2 Uchiyama *et al.*





Secondary effects



- **Electron mirror induced field due to higher band gap substrate heterostructure AlN/GaN – we see thinner GaN < 0.2 micron shows higher QE than > 1 micron thicker samples.**
- **Piezio strain field in GaN due to substrate mismatch – not confirmed**



GaN thermionic noise



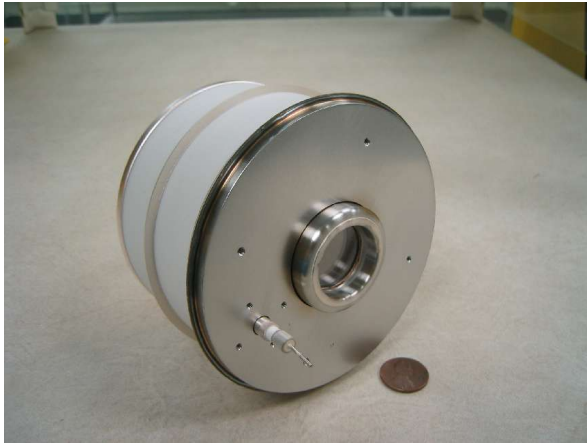
- **The noise of a wide band gap emitter without high internal fields (eg. a TE photocathode) such as GaN will be dominated by the electron diffusion current in the bulk absorber region multiplied by the thermalized electron escape probability.**
- **We are setting up a MCP based system to measure**
- **UCB – already measured few counts/cm/s.**



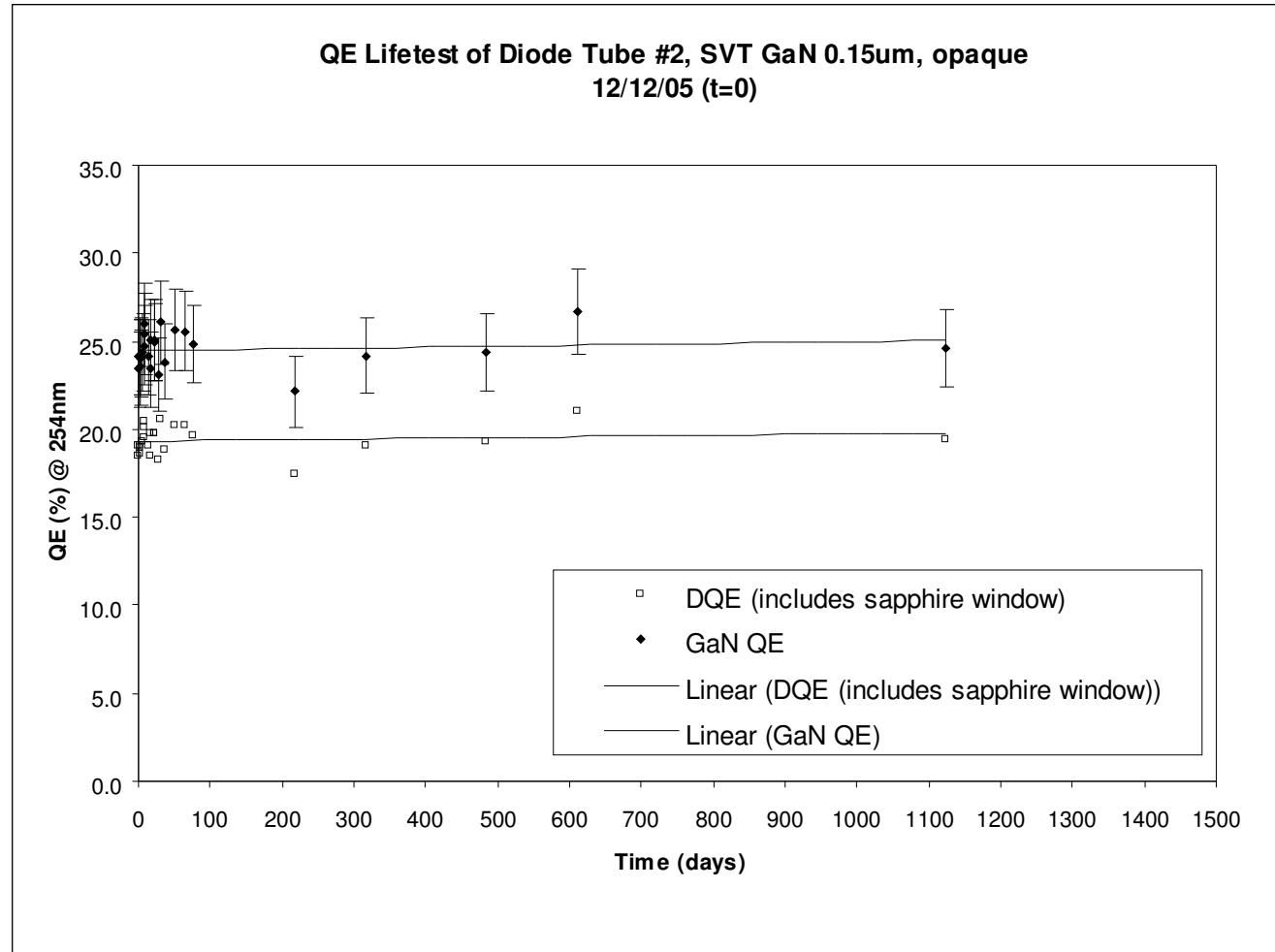
Quantum efficiency stability



Sealed tube – GaN quantum efficiency lifetime

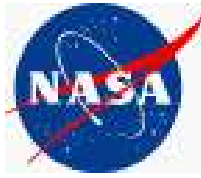


Can be assumed
long term
quiescent stability
demonstrated





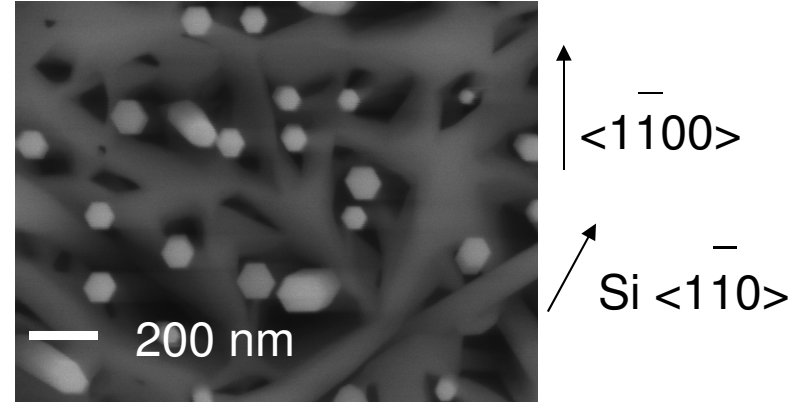
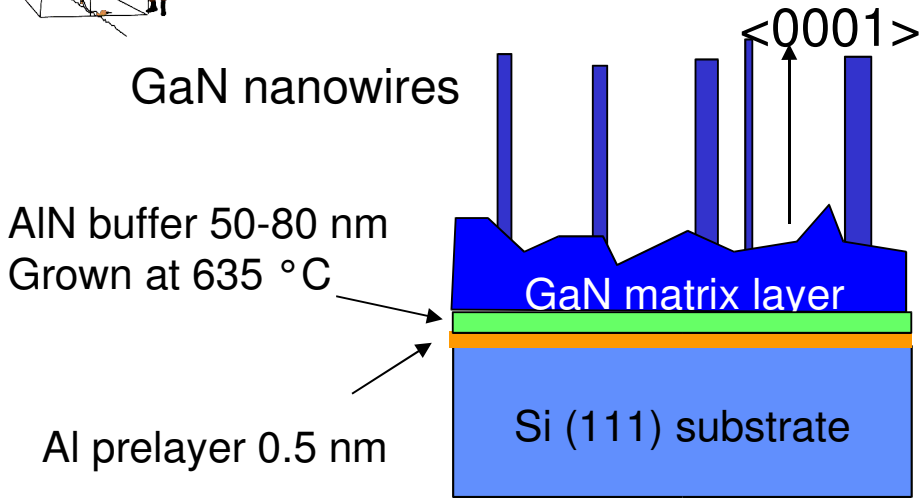
Nanowire structuring



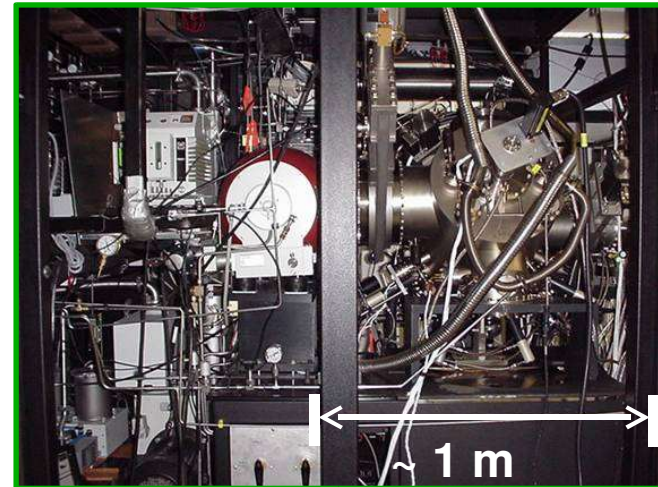
- **Nanowires may lead to higher QE due to :-**
- **Higher absorption – analogous to “Black Silicon”**
- **Much higher crystal purity – longer diffusion length and QE**
- **Can match a variety of layers eg Silicon MCP substrates.**



GaN nanowire (p-doped) at NIST, CO

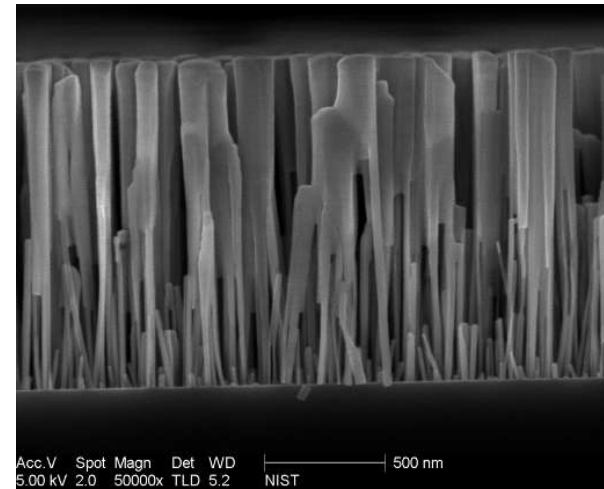
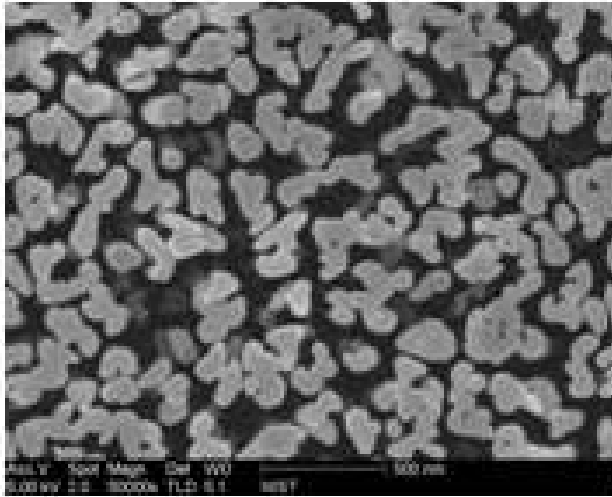


No catalyst
Wire growth in range 810 to 830 °C
MBE with plasma-assisted N₂ source
Low Ga flux and high nitrogen flux
Smaller wires have perfect hexagonal cross-section, aligned to substrate and therefore to each other
Both wire tips and matrix are Ga-face as determined by CBED and etching

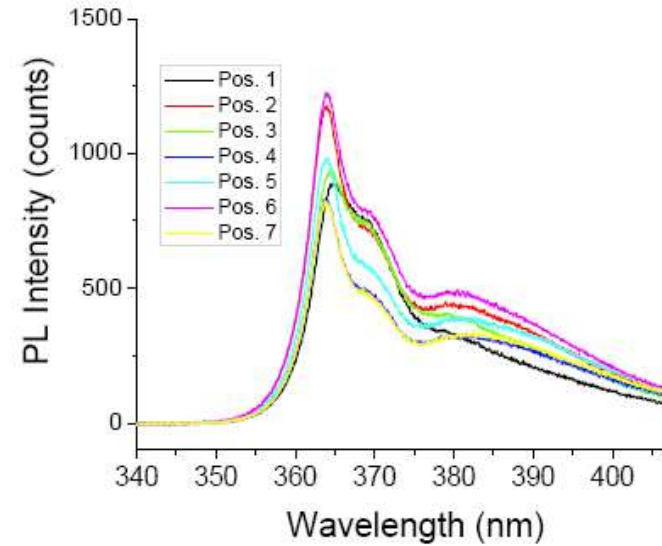




NIST, CO GaN Nanowires

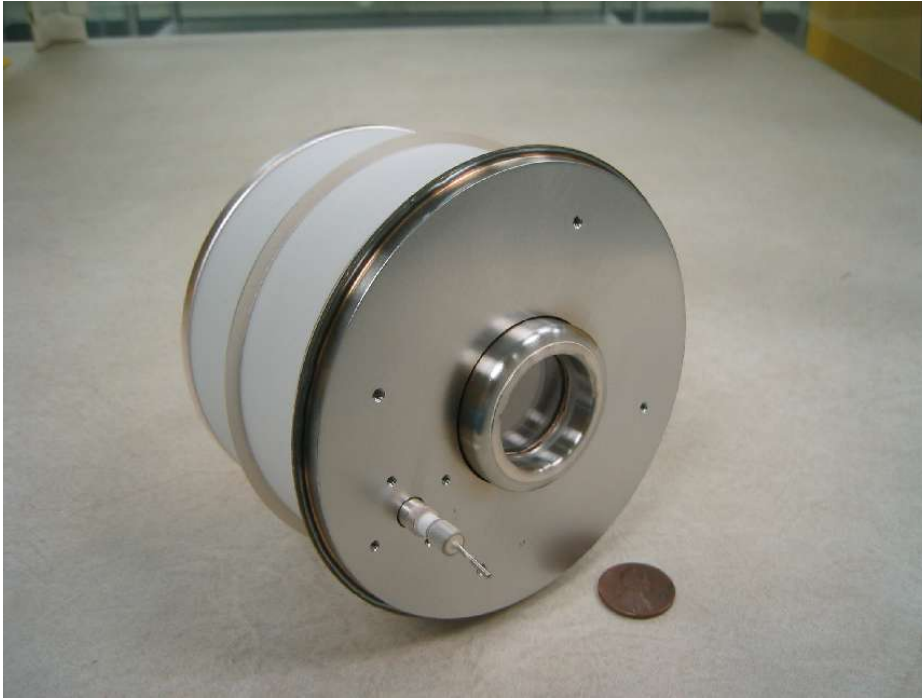
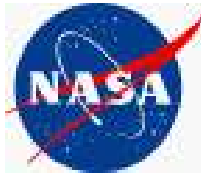


N130 As Grown Room-Temperature HeCd PL, 5-29-09



Recent sample shows un-cesiated QE > 30 % at 121nm

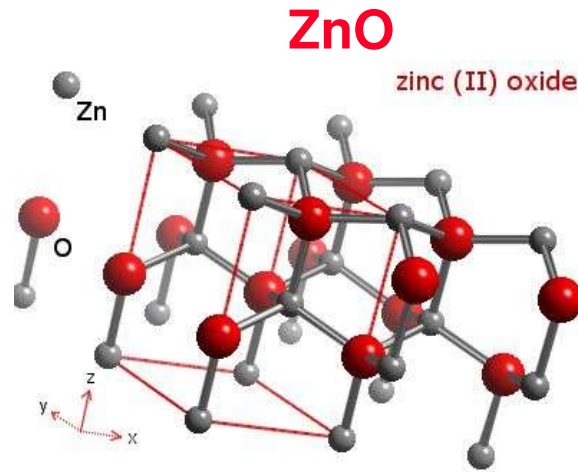
Detectors with GaN processed and sealed at GSFC



Diode tube



EBCCD tube – Photek
resealed by GSFC



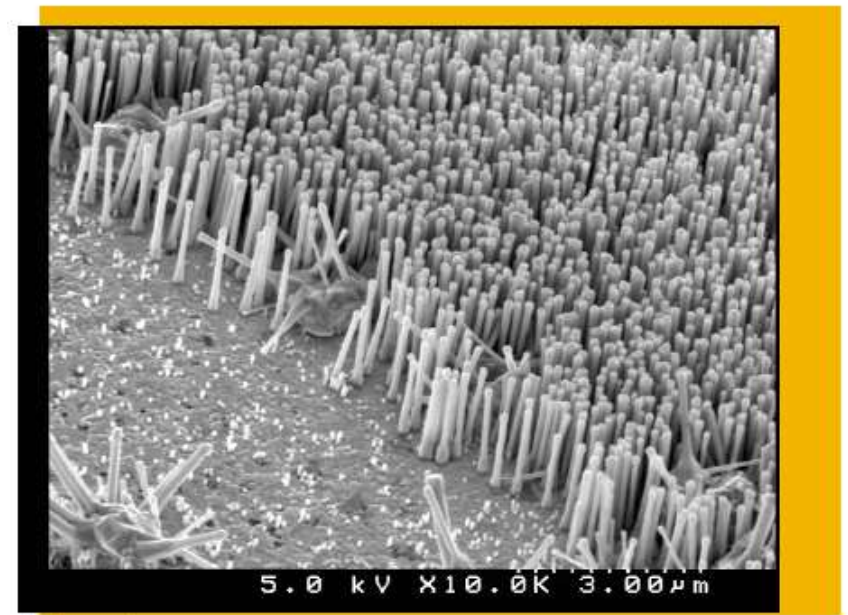
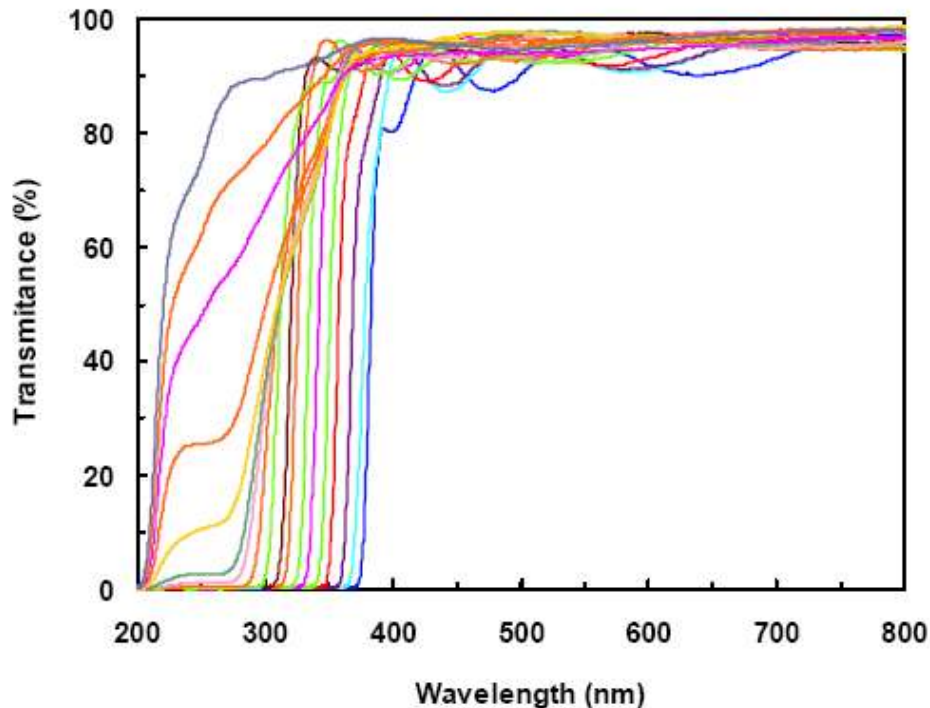
- **Potential advantages – much lower intrinsic defect levels than GaN, can be matched to a large variety of substrates, can be readily grown in nanowire configurations.**
- **Problems – intrinsically n-type difficulty in p-doping,– same solubility issues as GaN**
- **Phosphorous p-doping has recently been demonstrated by UMD.**



University of Maryland ZnO research

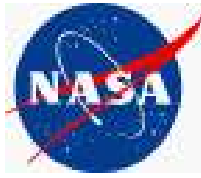


Wide band gap thin film $\text{Zn}_{(1-x)}\text{Mg}_x\text{O}$ system is capable of tuning a band gap from 3.3 eV to 7.9 eV for visible blind UV detection. Selective area growth of nanowires can be facilitated using diamond-like carbon film as a pattern and nucleation layer.





Conclusions



- **State of the art III-V opaque mode photocathodes eg GaN can attain very high QE in the NUV $> 72\%$, (as demonstrated by GSFC,UCB,Hamamatsu).**
- **p-Doping level is crucial in optimizing yield.**
- **Surface preparation also very important.**
- **Alloying with In or Al can extend wavelength response.**
- **Nanowire structuring may yield higher QE via improved diffusion length and reduced reflectivity and optimized absorption.**
- **Main challenge - matching to usable detector substrates including Silicon and Ceramic MCPS to be demonstrated.**